

ERRATUM

Optically monitoring and controlling nanoscale topography during semiconductor etching

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Correction to: *Light: Science & Applications* (2012) 1, e30; doi:10.1038/lisa.2012.30

This article, published on 28 September, should have been published with an accompanying supplementary information video file online.

This supplementary information file has now been published online; we apologize for the omission.